

**PATENT APPLICATION**  
**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of

Docket No: Q77434

Tsutomu SHOKI, et al.

Appln. No.: 10/658,372

Group Art Unit: 1756

Confirmation No.: 3326

Examiner: John S. Ruggles

Filed: September 10, 2003

For: METHOD OF PRODUCING A REFLECTIVE-TYPE MASK BLANK, METHOD OF  
PRODUCING A SEMICONDUCTOR DEVICE

**NOTICE OF APPEAL**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Applicant hereby appeals to the Board of Patent Appeals and Interferences from the final Office Action dated December 22, 2006.

The statutory fee of \$500.00 is being charged to Deposit Account No. 19-4880 via EFS Payment Screen. The USPTO is directed and authorized to charge all required fees, except for the Issue Fee and the Publication Fee, to Deposit Account No. 19-4880. Please also credit any overpayments to said Deposit Account. A duplicate copy of this sheet is enclosed.

Respectfully submitted,

*/Alan J. Kasper/*

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**23373**

CUSTOMER NUMBER

Date: June 21, 2007